

In re Application of  
RESTEK CORPORATION  
U.S. Patent Application  
Serial Nos. 10/642,866  
Filed: August 18, 2003



For: METHOD FOR CHEMICAL VAPOR DEPOSITION OF  
SILICON ON TO SUBSTRATES FOR USE IN CORROSIVE  
AND VACUUM ENVIRONMENTS

**DECLARATION OF GARY BARONE**

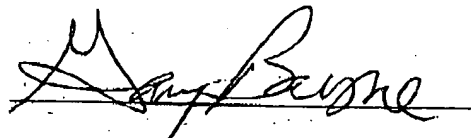
I, Gary Barone, do hereby declare and state that:

1. I am an inventor of the invention disclosed and claimed in U.S. Patent application serial no. 10/642,866.
2. I make this declaration in response to the Office Action of October 6, 2004.
3. At all times relevant to this matter, I have been employed with Restek Corporation of Bellefonte, Pennsylvania. Restek Corporation is the owner, by assignment, of U.S. Patent 6,511,760 B1, recorded at reel/frame 009929/0861. Restek Corporation is also the owner of the present invention, and above captioned patent application, through the assignment recorded at reel/frame 014408/0663.
4. The invention disclosed in U.S. Patent 6,511,760 B1 was derived from me and is thus not the invention of another.

I hereby declare that all statements made herein of my own knowledge are true and that all statements made on information and belief are believed to be true; and further that these statements were made with the knowledge that willful false statements and the like so made are punishable by fine or imprisonment, or both, under Section 1001 of Title 18 of the United States

Code and that such willful false statements may jeopardize the validity of the application or any patent issued thereon.

Dated: April 5, 2005

  
Gary Barone